

GAS | Products For Gas Applications

Products For
Gas Applications

MASS FLOW CONTROLLER

DeviceNet™ Mass Flow Controller MC-5000L Series



■ Outlines

- MC-5000L Series: DeviceNet™ interface-dedicated mass flow controller in accordance with SEMI

■ Features

- Widely-used sensor-actuator Networks DeviceNet™(ODVA) interface
- Top or side communication connectors installation available for selection
- LINTEC's unique ambient temperature-compensated sensor incorporated
- Highly functional upon installation of microprocessor
- Diaphragm valve with small dead volume
- High-speed and high performance piezoelectric actuator
- Long-term leak tightness ensured using metal seal
- By using metal case and various filters, stable operation can be achieved through reduction of radio frequency noises and electromagnetic field interferences

CE RoHS

Model	MC-5100L	MC-5200L	MC-5250L	MC-5460L	MC-5470L
Flow rate in Nitrogen (Full scale)	5 ~ 5,000SCCM	~ 20SLM	~ 50SLM	~ 150SLM	~ 200SLM
Flow rate control range	2 ~ 100% F.S.				
Valve operation mode	Normally open, Normally closed			Normally closed	
Accuracy	100% F.S. ~ 10% F.S. ±1.0% S.P. 10% F.S. ~ 2% F.S. ±0.1% F.S.			100% F.S. ~ 35% F.S. ±1.0% S.P. 35% F.S. ~ 2% F.S. ±0.35% F.S. ±1.0% F.S.	
Repeatability	±0.1% F.S.			±0.5% F.S.	
Response time	1 sec				
Operating differential pressure	50 ~ 300kPa	Normally open valve 50 ~ 300kPa (~ 10SLM) 100 ~ 300kPa (~ 20SLM) Normally closed valve 100 ~ 300kPa (~ 10SLM) 200 ~ 300kPa (~ 20SLM)	100 ~ 300kPa (~ 30SLM) 150 ~ 300kPa (~ 50SLM)	250 ~ 500kPa	350 ~ 500kPa
Withstand pressure	1MPa(G)				
Operating temperature	5 ~ 50°C 0 ~ 80% RH				
Leak integrity	1×10 ⁻¹¹ Pa·m ³ /sec He				
Materials exposed to gas	SUS316L, PCTFE, PTFE			SUS316L, SUS304, Teflon®, Viton®	
Seal materials	Au				
Power supply requirement	11 ~ 25VDC (5VA Max.)				
Mounting position	Free				
Digital interface	DeviceNet™				
Control valve actuator	Piezoelectric actuator				
Weight	1.0kg			1.4kg	